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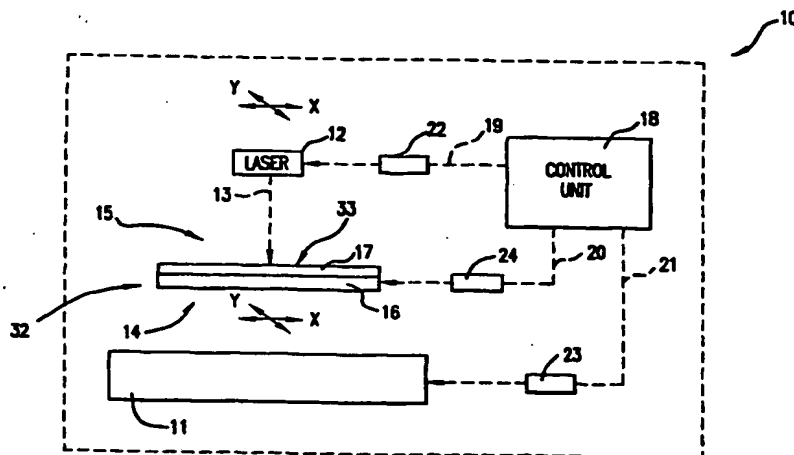
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(54) Title: MATERIAL DELIVERY SYSTEM FOR MINIATURE STRUCTURE FABRICATION



(57) Abstract: A material delivery system (10) is provided for miniature structures fabrication which has a substrate (11), a material carrier (15) having a deposition layer (16), and a laser beam (12) directed towards the material carrier element (15). A control unit (18) is operatively coupled to the substrate (11), the material carrier element (15) and laser beam (12) for exposing respective areas of the deposition layer (16) to the laser beam (12) in a patterned manner so that the depositable material (16) of the deposition layer (16) is transferred to the substrate (11) surface for deposition on its surface. The system (10) operates in either an additive mode of operation, or a subtractive mode of operation so that a workpiece (11) does not have to be removed from the tool when change of modes of operation takes place.

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